



PATENT

Customer No. 22,852

Attorney Docket No. 04329.2566

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

SHINICHI ITO et al.

Application No.: 09/842,403

Filed: April 26, 2001

For: FILM FORMATION METHOD, SEMICONDUCTOR  
ELEMENT AND METHOD THEREOF, AND  
METHOD OF MANUFACTURING A DISK-  
SHAPED STORAGE MEDIUM

Commissioner for Patents and Trademarks  
Washington, DC 20231

Sir:

**RESPONSE TO RESTRICTION REQUIREMENT**

In a restriction requirement dated August 28, 2002, the Examiner required  
restriction under 35 U.S.C. § 121 between:

Group I - Claims 1-18, 20, 22, and 23, and

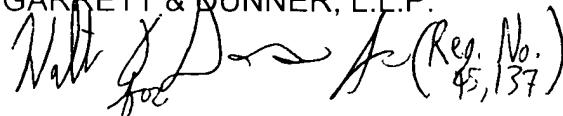
Group II - Claims 19 and 21.

Applicants provisionally elect to prosecute Group I, claims 1-18, 20, 22, and 23,  
drawn to a method of making a semiconductor device, without traverse.

Please grant any extensions of time required to enter this response and charge  
any additional required fees to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

  
(Reg. No. 45,137)

By:

Richard V. Burgujian  
Reg. No. 31,744

Dated: Sept 27, 2002

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